

# ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

## Title of Invention

METHOD OF PLANARIZING SPIN-ON MATERIAL LAYER AND  
MANUFACTURING PHOTORESIST LAYER

Application Number :

Confirmation Number:

First Named Applicant: Jefferson Lu

Attorney Docket Number: 12474-US-PA

Art Unit:

Examiner:

Search string: ( 6482716 or 6630397 ).pn

## US Patent Documents

**Note: Applicant is not required to submit a paper copy of cited US Patent Documents**

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6482716	2002-11-19	Wohlfahrt et al.		438	427
	2	6630397	2003-10-07	Ding et al.		438	636

## Signature

Examiner Name	Date